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Amendments to the Claims

This listing of claims replaces all prior versions and listings of claims in the application.

Listing of Claims

1-19. (Canceled)

20. (Previously Presented) A method of depositing a layer in a deposition apparatus, the deposition apparatus comprising:

a load chamber;

an alignment chamber;

a first deposition chamber for forming an organic compound layer on a first electrode, prepared with a first and a second evaporation sources and a light source;

a cleaning preliminary chamber;

a second deposition chamber for forming a second electrode; and

a sealing chamber,

wherein the first evaporation source comprises a first organic compound; and wherein the second evaporation source comprises a second organic compound; the method comprising:

forming a first function region comprising the first organic compound evaporated from the first evaporation source over the first electrode in the first deposition chamber during irradiation with light from the light source;

forming a mixed region comprising the first organic compound evaporated from the first evaporation source and the second organic compound evaporated from the second evaporation source on the first function region in the first deposition chamber during irradiation with light from the light source;

forming a second function region comprising the second organic compound evaporated from the second evaporation source but not from the first evaporation source on the mixed region in the first deposition chamber during irradiation with light from the light source.

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21-50. (Canceled)

51. (Previously Presented) A method of depositing a layer in a deposition apparatus, the deposition apparatus comprising:

a load chamber;

an alignment chamber;

a first deposition chamber for forming an organic compound layer on a first electrode, prepared with a first and a second evaporation sources and a light source;

a cleaning preliminary chamber;

a second deposition chamber for forming a second electrode; and

a sealing chamber,

wherein the first evaporation source comprises a first organic compound; and wherein a second evaporation source comprises a second organic compound; the method comprising:

forming a first function region comprising the first organic compound evaporated from the first evaporation source over the first electrode in the first deposition chamber;

forming a mixed region comprising the first organic compound evaporated from the first evaporation source and the second organic compound evaporated from the second evaporation source on the first function region in the first deposition chamber during irradiation with light from the light source; and

forming a second function region comprising the second organic compound evaporated from the second evaporation source but not from the first evaporation source on the mixed region in the first deposition chamber,

wherein the mixed region includes organic compound molecules; and wherein the light is irradiated to the mixed region so as to activate the organic compound molecules and promote for compact film formation.

52. (Previously Presented) A method of depositing a layer according to claim 51, wherein a light irradiated from the light source is an ultraviolet ray.

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53. (Previously Presented) A method of depositing a layer according to claim 51, wherein the light source is a low-pressure mercury lamp.

54. (Previously Presented) A method of depositing a layer according to claim 51, wherein a light irradiated from the light source has a wavelength of 100 nm to 300 nm.

55-64. (Canceled)